## AMENDMENT UNDER 37 C.F.R. § 1.111 U.S. Application No.: 09/900,962

Attorney Docket No.: Q61744

producing a gallium nitride-based compound semiconductor layer doped with a p-type impurity;

producing a catalyst layer comprising a metal, alloy or compound on said gallium nitride-compound semiconductor layer;

annealing the gallium nitride-based compound semiconductor layer fixed with said catalyst layer in an atmosphere gas containing no oxygen;

stripping said catalyst layer completely; and providing a p-side electrode on said p-type layer after annealing.